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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Pei Reng Jeng, et al.

Serial No.: 09/781,283

Filed: 13 February 2001

Title

: PLANARIZATION METHOD OF INTER-

LAYER DIELECTRICS AND INTER-METAL

**DIELECTRICS** 

: Art Unit #2823

: Examiner:

: M. Estrada

## **AMENDMENT**

Mail Stop Non-Fee Amendment Honorable Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Responsive to the Official Action dated 10 February 2003, please amend the above-referenced Patent Application as follows:

## IN THE CLAIMS:

Please replace Claims 1 and 9 with the "CLEAN COPY" of the amended Claims as follows:

## **CLEAN COPY OF AMENDED CLAIMS**

1. (Four Times Amended) A planarization method of inter-layer dielectrics, comprising the steps of:

providing a semiconductor substrate including a field oxide, a source, a drain, and a gate formed thereon;



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